

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Young-Man JEONG et al.

Application No.: 10/565,107

Confirmation No.: 5526

Filed: March 5, 2007

Art Unit: 1792

For: PLASMA SURFACE PROCESSING SYSTEM
AND SUPPLY DEVICE FOR PLASMA
PROCESSING SOLUTION THEREFOR

Examiner: K. T. Chen

AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office Action dated July 11, 2008, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 12 of this paper.